

INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i>		Docket Number (Optional) TWI-33010	Application Number <u>NEW 101767,792</u>
		Applicant(s) Kenneth C. Johnson	
		Filing Date Herewith	Group Art Unit <u>Unknown 2842</u>

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
Tony	*AA	5,963,329	10/05/99	Conrad et al.	356	372	10/31/97
Adri	*AB	6,268,916	07/31/01	Lee et al.	356	369	05/11/99
Mel	*AC	6,590,656	07/08/03	Xu et al.	356	369	09/21/01
Tom	*AD	5,867,276	02/02/99	McNeil et al.	356	445	03/07/97
Tom	*AE	2001/0051856	12/13/01	Niu et al.	702	57	01/17/01
Tom	*AF	2002/0038196	03/28/02	Johnson et al.	702	179	08/10/01
Tom	*AG	2002/0158193	10/31/02	Sezginer et al.	250	237	02/12/02
Tom	*AH	2003/0147086	08/07/03	Rosencwaig et al.	356	601	09/13/02
Tom	*AI	2003/0204326	10/30/03	Opsal et al.	702	28	04/02/03
Tom	*AJ	2003/0076511	04/24/03	Aikens et al.	356	636	05/14/02

FOREIGN PATENT DOCUMENTS

REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	No
AK	WO 03/009063	01/30/03	PCT	G03F	7/20		X
AL	WO 03/054475	07/03/03	PCT	G01B	11/06		x
AM	WO 02/27288	04/04/02	PCT	G01J	3/28		x

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

Initial	AN	C.J. Raymond, "Scatterometry for Semiconductor Metrology", Handbook of Silicon Semiconductor Metrology, A. Diebold, Ed., New York 2001, Chapter 18, pp. 477-513 <i>[initials]</i>					

Examiner <i>Kelvin Johnson</i>	Date Considered <i>8-18-05</i>
Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	